

PROCEEDINGS OF SPIE

Emerging Digital Micromirror Device Based Systems and Applications XIII

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Editors

6–11 March 2021
Online Only, United States

Cosponsored by
DLP Texas Instruments (United States)

Published by
SPIE

Volume 11698

Proceedings of SPIE 0277-786X, V. 11698

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

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Author(s), "Title of Paper," in *Emerging Digital Micromirror Device Based Systems and Applications XIII*, edited by John Ehmke, Benjamin L. Lee, Proceedings of SPIE Vol. 11698 (SPIE, Bellingham, WA, 2021) Seven-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510642317

ISBN: 9781510642324 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) Fax +1 360 647 1445

SPIE.org

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